

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hidemitsu ASANO et al.

Group Art Unit: 2613

Application No.: 10/726,686

Filed: December 4, 2003

Docket No.: 106298.01

For: MEASURING METHOD, MEASURING SYSTEM AND STORAGE MEDIUM

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. The references 1-6 were cited in a counterpart foreign application. An English language version of the foreign search report is attached for the Examiner's information.
- ☒ 3. JP A 06-161533 (reference 3 in the foreign search report) was previously submitted in an Information Disclosure Statement, and is therefore not attached.

Respectfully submitted, -



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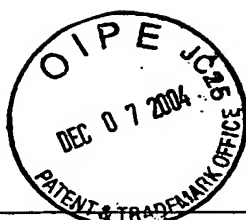
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DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461
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Sheet 1 of 1

Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 106298.01		APPLICATION NO. 10/726,686	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANTS Hidemitsu ASANO et al.			
				FILING DATE December 4, 2003		GROUP 2613	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
	1	Fang et al., "Stereo Vision and CMM Integrated Intelligent Inspection System in Reverse Engineering", PROCEEDINGS OF THE SPIE - THE INTERNATIONAL SOCIETY FOR OPTICAL ENGINEERING, Vol. 3521, November 4, 1998, pages 115-122					
	2	Chan et al., "Neural Network Stereo Image Segmentation for Directed Coordinate Measuring Machine Part Programming", IEEE PACIFIC RIM CONFERENCE ON COMMUNICATIONS, COMPUTERS AND SIGNAL PROCESSING, August 20, 1997, pages 547-550					
	3	Wang et al., "A vision-aided alignment datum system for coordinate measuring machines", MEASUREMENT SCIENCE AND TECHNOLOGY, Vol. 8, No. 7, July 1, 1997, pages 707-714					
	4	Oltzsch et al., "Hochauflösende Bildmeßtechnik - High resolution imaging technology", TECHNISCHES MESSEN TM, Vol. 60, No. 5, May 1, 1993, pages 204-210					
	5	Wang et al., "The use of a machine vision system in a flexible manufacturing cell incorporating an automated coordinate measuring machine", PROCEEDINGS OF THE INSTITUTION OF MECHANICAL ENGINEERS, PART B, Vol. 207, No. B3, 1993, pages 199-202					
	6	Labs, "Laser sensors pay off in accuracy", I & CS - INDUSTRIAL AND PROCESS CONTROL MAGAZINE, Vol. 64, No. 7, July 1, 1991, pages 51-53					
EXAMINER					DATE CONSIDERED		
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

Date: December 7, 2004